

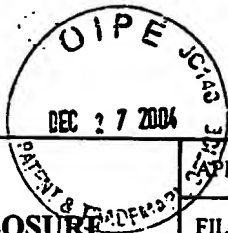
FORM PTO-1449/A and B (Modified)		APPLICATION NO.: 09/975,169	ATTY. DOCKET NO.: P0743/7001
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		FILING DATE: October 11, 2001	
		APPLICANT: Erik Deutsch et al.	
		GROUP ART UNIT: 2872	EXAMINER: Not Yet Assigned
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<i>[Signature]</i>		EP	1 143 287 A2			10-10-2001	

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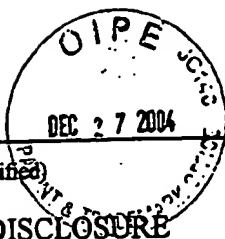
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<i>[Signature]</i>		<u>ANALYSIS OF GRATING LIGHT VALVES WITH PARTIAL SURFACE ELECTRODES</u> , FURLANI et al., J. Appl. Phys. 83 (2), 01/15/98, American Institute of Physics, pp 629-634	

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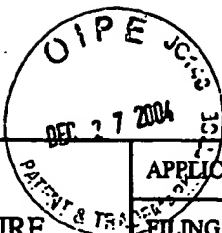
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		<u>MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON</u> , K.E. PETERSEN, IBM Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	
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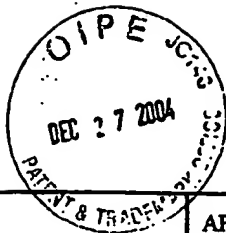
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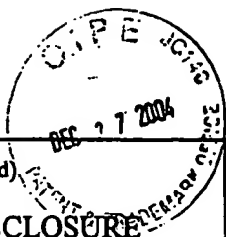
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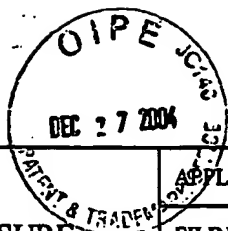
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			APPLICANT: Erik R. Deutsch et al.			
			GROUP ART UNIT: 2872		EXAMINER:	
Sheet	6	of	6			

U.S. PATENT DOCUMENTS

Examiner's Initials #	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YY
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FOREIGN PATENT DOCUMENTS

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OTHER ART — NON PATENT LITERATURE DOCUMENTS

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apl		<u>SYNTHETIC SPECTRA: A TOOL FOR CORRELATION SPECTROSCOPY</u> , SINCLAIR et al., Applied Optics, Vol. 36, No. 15 05/20/97, pp 3342-3348		
		<u>SYNTHETIC INFRARED SPECTRA</u> , SINCLAIR et al., Optical Society of America, Optical Letters, vol. 22, No. 13 07/01/97, pp 1036-1038		
		<u>THE POLYCHROMATOR: A MEMS CORRELATION SPECTROMETER</u> , HUNG et al., Microsystems Technology Laboratories Annual Report 1998,		
		<u>MEMS: RESEARCH AND APPLICATIONS IN MICROELECTROMECHANICAL SYSTEMS</u> , HUNG et al., Poster Session Guidebook, 03/31/98, pp 1 and 4		
apl		<u>EXTENDING THE TRAVEL RANGE OF ANALOG-TUNED ELECTROSTATIC ACTUATORS</u> , HUNG et al., IEEE J. of Microelectromechanical Systems, vol. 8, No. 4, December 1999, pp497-505		

EXAMINER <i>Cherry</i>	DATE CONSIDERED <i>2/21/05</i>
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